

APR 15 2003

THE UNITED STATES PATENT AND TRADEMARK OFFICE

2811
#16/D
Suppl. Amendment
J. Robinson
5/9/03

In re Patent Application of)
Shunpei YAMAZAKI et al.) Group Art Unit: 2811
Serial No. 09/535,015) Examiner: S. Crane
Filed: March 24, 2000)
For: METHOD OF MANUFACTURING)
A SEMICONDUCTOR DEVICE)

CERTIFICATE OF MAILING

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Washington, D.C. 20231 on 4-11-2003

Adele M. Stamper

SUPPLEMENTAL AMENDMENT

Honorable Commissioner for Patents
Washington, D.C. 20231
Sir:

Further in response to the Office Action dated October 23, 2002, and the
Amendment filed February 24, 2003, please amend the above-identified application as
follows:

IN THE SPECIFICATION:

Please amend the specification as follows:

Please replace the paragraph bridging page 4 and 5 with the following:

According to the present invention disclosed in the present specification, chlorine is
also contained in the atmosphere in order to promote the effect of gettering the metal. The
effect of eliminating the metal element from the silicon film may be enhanced by forming a
compound of the metal element, fluorine and chlorine at the time of gettering by
introducing chlorine.